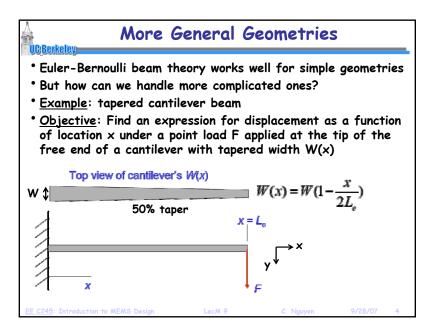
EE 245: Introduction to MEMS

Lec18m1: Energy Methods



Shear Strain Energy $W_{host} = \frac{3(EI_z)^2}{4GWh} \int_0^L \left(\frac{d^3y}{dx^3}\right)^2 dx$ Shear Modulus * See W.C. Albert, "Vibrating Quartz Crystal Beam Accelerometer," Proc. ISA Int. Instrumentation Symp., May 1982, pp. 33-44

Solution: Use Principle of Virtual Work

- In an energy-conserving system (i.e., elastic materials), the energy stored in a body due to the quasi-static (i.e., slow) action of surface and body forces is equal to the work done by these forces ...
- <u>Implication</u>: if we can formulate <u>stored energy</u> as a function of the deformation of a mechanical object, then we can determine how an object responds to a force by determining the shape the object must take in order to <u>minimize</u> the <u>difference U</u> between the stored energy and the work done by the forces:

U = Stored Energy - Work Done

 <u>Key idea</u>: we don't have to reach U = 0 to produce a very useful, approximate analytical result for load-deflection

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Applying the Principle of Virtual Work

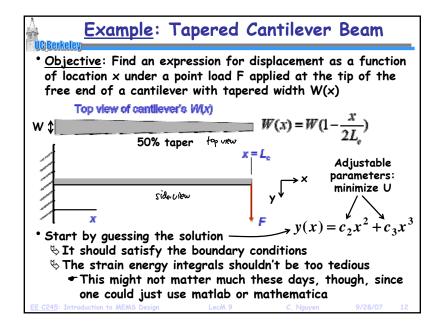
- * Basic Procedure:
 - Guess the form of the beam deflection under the applied loads
 - Vary the parameters in the beam deflection function in order to minimize:

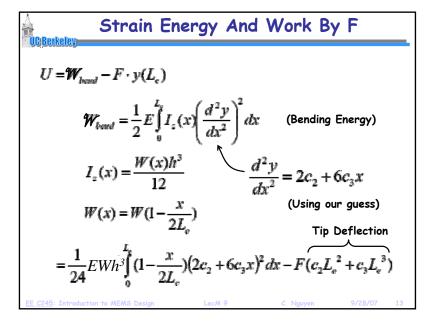
Sum strain energies point load
$$U = \sum_{j} W_{j} - \sum_{i} F_{i} u_{i}$$
 Displacement at point load

- \$ Find minima by simply setting derivatives to zero
- See Senturia, pg. 244, for a general expression with distributed surface loads and body forces

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Find c_2 and c_3 That Minimize U

- Minimize U → basically, find the c₂ and c₃ that brings U closest to zero (which is what it would be if we had guessed correctly)
- The c_2 and c_3 that minimize U are the ones for which the partial derivatives of U with respective to them are zero:

$$\frac{\partial U}{\partial c_2} = 0 \qquad \frac{\partial U}{\partial c_3} = 0$$

• Proceed:

♥ First, evaluate the integral to get an expression for U:

$$U = EWh^{3} \left\{ \frac{5c_{3}^{2}}{16} L_{e}^{3} + \frac{c_{2}c_{3}}{3} L_{e}^{2} + \frac{c_{2}^{2}}{8} L_{e} \right\} - F(c_{2}L_{e}^{2} + c_{3}L_{e}^{3})$$

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C. Ngu

9/28/07 14

Minimize U (cont)

Evaluate the derivatives and set to zero:

$$\frac{\partial U}{\partial c_2} = 0 = \left(\frac{EWh^3}{3}c_3 - F\right)L_e^2 + \left(\frac{EWh^3}{4}c_2\right)L_e$$

$$\frac{\partial U}{\partial c_3} = 0 = \left(\frac{5}{8}EWh^3c_3 - F\right)L_e^3 + \left(\frac{EWh^3}{3}c_2\right)L_e^2$$

ullet Solve the simultaneous equations to get c_2 and c_3 :

$$c_2 = \left(\frac{84}{13}\right) \frac{FL_c}{EWh^3} \qquad c_3 = -\left(\frac{24}{13}\right) \frac{F}{EWh^3}$$

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LecM 9

C. Nguyen

9/28/07 15

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The Virtual Work-Derived Solution

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* And the solution:

$$y(x) = \left(\frac{24F}{13EWh^3}\right) \left(\frac{7}{2}\right) L_o - x x^2$$

• Solve for tip deflection and obtain the spring constant:

$$y(L_e) = \left(\frac{24F}{13EWh^3}\right)\left(\frac{5}{2}\right)L_e^3$$
 $k_e = F/y(L_e) = \left(\frac{13EWh^3}{60L_e^3}\right)$

 Compare with previous solution for constant-width cantilever beam (using Euler theory):

$$y(L_e) = \left(\frac{4F}{EWh^3}\right) L_e^3 \longrightarrow 13\%$$
 smaller than tapered-width case

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LecM 9

9/28/07

Need a Better Approximation?

- Add more terms to the polynomial
- Add other strain energy terms:
 - Shear: more significant as the beam gets shorter
 - & Axial: more significant as deflections become larger
- Both of the above remedies make the math more complex, so encourage the use of math software, such as Mathematica, Matlab, or Maple
- Finite element analysis is really just energy minimization
- If this is the case, then why ever use energy minimization analytically (i.e., by hand)?
 - Analytical expressions, even approximate ones, give insight into parameter dependencies that FEA cannot
- & Can compare the importance of different terms
- Should use in tandem with FEA for design

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LecM 9

C. Nguyen

9/28/07 18

